



PATENT

Attv. Dkt. No. AMAT/5027.02/CPI/COPPER/PJS

In re Application of:
Chen, et al.

Serial No.: 10/050,654

Confirmation No.: 6065

Filed: January 16, 2002

For: Method for Growing Thin
Films by Catalytic
Enhancement

Group Art Unit: 1762

Examiner: Timothy H. Meeks

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING
37 CFR 1.8

I hereby certify that this correspondence is being deposited on 4/19/04 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

4/19/04

Date _____

Kind 2

Signature

Dear Sir:

RESPONSE TO FINAL OFFICE ACTION DATED FEBRUARY 19, 2004

In response to the Final Office Action dated February 19, 2004, having a shortened statutory period for response set to expire on May 19, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Commissioner is hereby authorized to charge Deposit Account No. 20-0782/AMAT/5027.02/KMT in the amount of \$110.00, for a statutory disclaimer fee, along with any other fees to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 5 of this paper.